structures 18 which are essentially constituted by troughshaped indentations 20. In accordance with the embodiment shown in FIG. 3, the trough-shaped indentation 20 has a plane bottom surface 22 on which the sensor element 12 is arranged. In accordance with the embodiment shown in FIG. 4, the surface 22 is provided with a pedestal-like elevation 24 on which the sensor element 12 is arranged.

[0018] FIG. 5 shows a variant in which the magnet 14 has a convex symmetrical shape with respect to the sensor element 12, while the surface 22 is convex in the y direction. In the area of the sensor chip 12, the surface 22 is, however, plane. An analog variant is shown in FIG. 6 in which the surface 22 is convex in the x direction. Furthermore, the supporting magnet 14 is wedge-shaped in the x direction.

[0019] Embodiments other than the ones shown in the Figures are possible within the scope of the invention. Differently chosen structures of the magnets 14 are of course also feasible when it is thereby achieved that the magnetic flux lines 25 of the magnet 14 perpendicularly to the surface 16, i.e. perpendicularly to the x/y plane, emerge from the magnet 14 in the area of the sensor element 12.

[0020] This is shown by way of example in FIG. 7 with reference to the magnet 14 shown in FIG. 3. The Figure is a sectional view of the magnet 14 with the indentation 20 constituting the structure 18. In this representation, the plane of the drawing coincides with the y/z plane. It is clear from the Figure that the indentation 20 deflects the magnetic flux lines 25 outside the magnet 14 in such a way that the magnetic flux lines 25 emerge essentially perpendicularly to the surface 16 without any deflection in the y direction in the sensitive area 26, i.e. in the area in which the sensor element 12 is arranged. This leads to only a minimal magnetic field H_y in the sensitive area 26. This quasi-unavailable magnetic field H_y can therefore not lead to an offset of the sensor element 12 in its sensing direction, i.e. in the y direction.

1. A magnetoresistive sensor comprising at least one sensor element for measuring a magnetic field, and a magnet assigned to the sensor element, characterized in that the

- magnet (14) has structures (18) which lead to a perpendicular guidance of magnetic flux lines (25) from the magnet (14) in the sensing direction (y direction) at least in the sensitive area (26) of the sensor (100).
- 2. A magnetoresistive sensor as claimed in claim 1, characterized in that the structures (18) are formed in a surface (16) facing the at least one sensor element (12).
- 3. A magnetoresistive sensor as claimed in claim 1, characterized in that the magnetic flux lines (25) are guided perpendicularly with respect to the surface (positioning plane) (16) in the sensitive area (26).
- 4. A magnetoresistive sensor as claimed in claim 1, characterized in that the surface (16) comprises a trough-shaped indentation (20) in which the sensor element (12) is arranged.
- 5. A magnetoresistive sensor as clamed in claim 1, characterized in that the indentation (20) has a plane bottom surface (22).
- 6. A magnetoresistive sensor as claimed in claim 1, characterized in that the bottom surface (22) constitutes a pedestal-like elevation (24) for accommodating the sensor element (12).
- 7. A magnetoresistive sensor as claimed in claim 1, characterized in that the indentation (20) has a concave shape.
- **8**. A magnetoresistive sensor as claimed in claim 7, characterized in that the concave shape extends in the y direction.
- **9.** A magnetoresistive sensor as claimed in claim 7, characterized in that the concave shape extends in the x direction.
- 10. A magnetoresistive sensor as claimed in claim 1, characterized in that the overall magnet (14) is concave-shaped with respect to the surface (16).
- 11. A magnetoresistive sensor as claimed in claim 1, characterized in that the supporting magnet (14) is wedge-shaped.

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